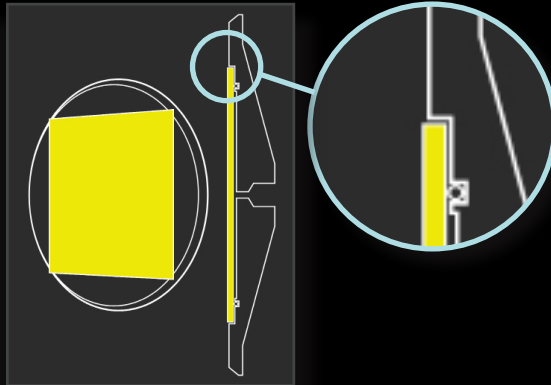


# Vacuum Chucks

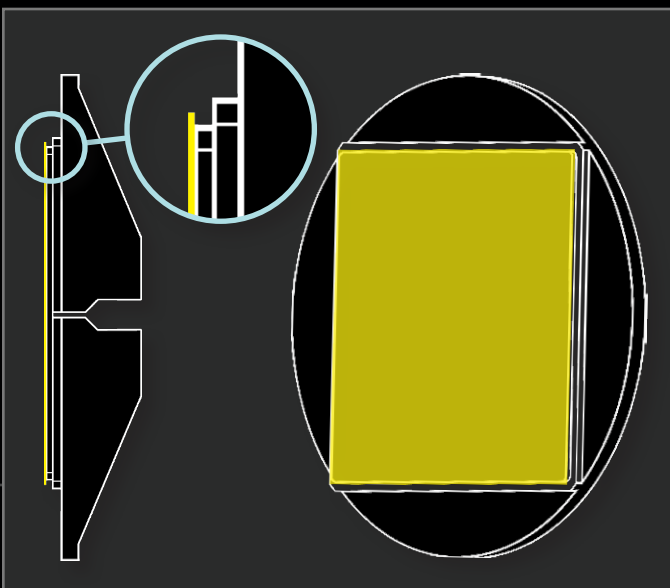
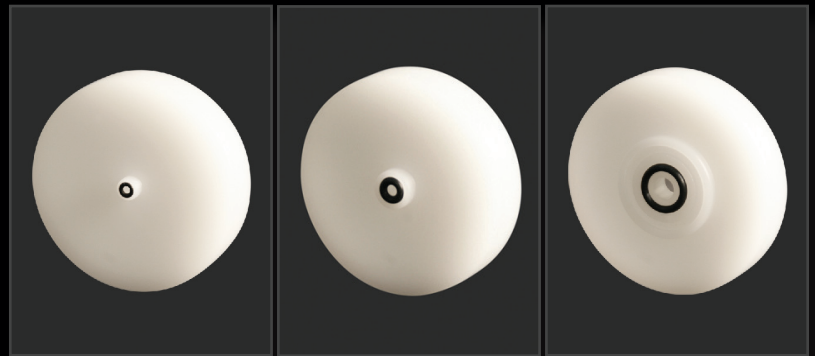


## Embedded Vacuum

Vacuum hold, centering and increased uniformity for thick and non-round substrates.

## Fragment Adapters

Support small substrates from 3 mm to 45 mm.



## High Porosity

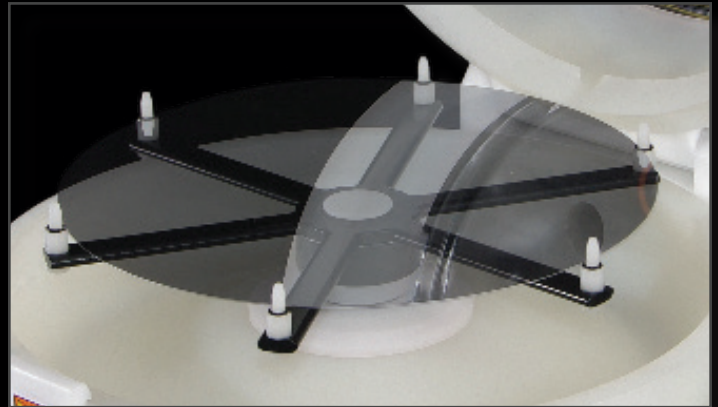
A **Laurell Technologies exclusive** design allows our high porosity chucks to hold thin films, fragile substrates, and thermally sensitive materials securely.

# Non-Vacuum Chucks



## Minimum Contact

**Laurell Technologies** mechanical pin chucks hold substrates securely, with the smallest possible contact area.



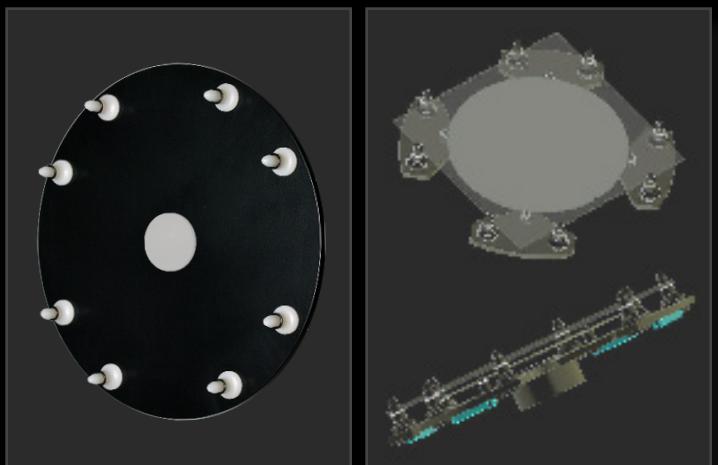
## Simultaneous Front & Backside Processing

Open, mechanical chucks allow full access to the substrate for etching, developing, or cleaning.



## Special Applications

Do you have a unique substrate you would like to coat, etch, develop, or clean? We have engineered solutions for thousands of customers, let us put our 28 years of experience at your service.



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